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APPLICATION NO. FIRST NAMED INVENTOR FILING DATE ATTORNEY DOCKET NO. 09/002.178 12/31/97 BOHR M 042390P4220 **EXAMINER** MM12/0818 -MICHAEL A BERNADICOU GUERRERO.M BLAKELY SOKOLOFF TAYLOR ZAFMAN ART UNIT PAPER NUMBER 12400 WILSHIRE BOULEVARD -7TH FLOOR 2822 LOS ANGELES CA 90025

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Please find below and/or attached an Office communication concerning this application or proceeding.

Commissioner of Patents and Trademarks

Application No. 09/002,178

Applicant(s)

Office Action Summary Examiner

Maria Guerrero

Group Art Unit 2822

Bohr



Responsive to communication(s) filed on Mar 8, 1999	·
This action is FINAL.	
Since this application is in condition for allowance except in accordance with the practice under Ex parte Quayle, 19	935 C.D. 11; 453 O.G. 213.
shortened statutory period for response to this action is se longer, from the mailing date of this communication. Failu pplication to become abandoned. (35 U.S.C. § 133). Exten 7 CFR 1.136(a).	t to expire3 month(s), or thirty days, whichever re to respond within the period for response will cause the
isposition of Claims	
X Claim(s) 1-20	
	is/are withdrawn from consideration.
Claim(s)	
X Claim(s) 1-20	
Claim(s)	
☐ Claims	are subject to restriction or election requirement.
Application Papers See the attached Notice of Draftsperson's Patent Drave The drawing(s) filed on	rity under 35 U.S.C. § 119(a)-(d).
☐ received in Application No. (Series Code/Serial ☐ received in this national stage application from *Certified copies not received:	the International Bureau (PCT Rule 17.2(a)).
Acknowledgement is made of a claim for domestic pr	riority under 35 U.S.C. § 119(e).
Attachment(s) Notice of References Cited, PTO-892 Information Disclosure Statement(s), PTO-1449, Paper Interview Summary, PTO-413 Notice of Draftsperson's Patent Drawing Review, PTO-152	
SEE OFFICE ACTION	ON THE FOLLOWING PAGES

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DETAILED ACTION

1. This Office Action is in response to Election and Amendment filed January 25, 1999.

Election/Restriction

- 2. Applicant's election without traverse of Group II, claims 1-20 in Paper No. 5 is acknowledged.
- 3. Claims 21-30 are canceled.

Drawings

4. Figure 1 should be designated by a legend such as --Prior Art-- because only that which is old is illustrated. See MPEP § 608.02(g).

Claim Objections

5. Claim 14 is objected to because of the following informalities: the claim recited "electroplating plating"; in line 2. Appropriate correction is required.

Claim Rejections - 35 USC § 112

6. The following is a quotation of the second paragraph of 35 U.S.C. 112:

The specification shall conclude with one or more claims particularly pointing out and distinctly claiming the subject matter which the applicant regards as his invention.

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7. Claims 1-5 and 11-20 are rejected under 35 U.S.C. 112, second paragraph, as being indefinite for failing to particularly point out and distinctly claim the subject matter which applicant regards as the invention.

Claim 1 recites "a semiconductor substrate", lines 1-2; "a substrate", lines 2-3. It is unclear if the claim is referring to the same semiconductor substrate.

Claim 11 recites the limitation "said second dielectric and said first dielectric" in lines 9-10.

There is insufficient antecedent basis for this limitation in the claim.

Claim Rejections - 35 USC § 102

8. The following is a quotation of the appropriate paragraphs of 35 U.S.C. 102 that form the basis for the rejections under this section made in this Office action:

A person shall be entitled to a patent unless --

- (b) the invention was patented or described in a printed publication in this or a foreign country or in public use or on sale in this country, more than one year prior to the date of application for patent in the United States.
- 9. Claims 1, 3-5 are rejected under 35 U.S.C. 102(b) as being anticipated by Kunieda et al. (U.S. 4,941,810).
- 10. Kunieda et al. discloses forming a first dielectric layer 16 (dielectric constant is 4) over a metal interconnect layer on a substrate 10, the metal interconnect layer including a bond pad and a metal member space apart from the bond pad by a gap (see fig. 1), forming a second dielectric layer 18 (dielectric constant is 8); the dielectric constant of the second dielectric layer is larger

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than the first dielectric layer (see col. 1, lines 50-68, col. 2, lines 28-35) (the second dielectric layer being hermetic, it is inherent). It is also teaching, the first dielectric layer comprises silicon dioxide; the second dielectric layer comprises silicon nitride; the second dielectric layer is thinner than the first dielectric layer (see col. 1, lines 65-68).

11. Claims 1, 3-4 are rejected under 35 U.S.C. 102(b) as being anticipated by Byrne (U.S. 5,369,299).

Byrne teaches a first dielectric layer 30A (silicon dioxide), a second dielectric layer 30B (silicon nitride layer) (it is known in the art than silicon nitride has a higher dielectric constant than silicon oxide), a metal interconnect layer on a substrate, the metal interconnect layer including a bond pad 24, and a metal member 23 spaced apart by a gap; the protective seals keeps out moisture (see fig. 1, Abstract, col. 3, lines 35-60, col. 4, lines 45-65).

- 12. Claim 11 is rejected under 35 U.S.C. 102(b) as being anticipated by Havemann (U.S. 5,565,384).
- 13. Havemann discloses conductors 18 separated by gap 20; forming a first dielectric layer 22 wherein said gap is completely filled by the first dielectric layer, forming a second dielectric layer 24 over the first dielectric layer 22, the second dielectric layer has a higher dielectric constant (3.9) than the first dielectric layer, forming an opening through said second dielectric layer and said first dielectric layer to exposed the top surface of at least one of the spaced apart members (see figs. 1A-1D). Referring to fig. 7, it is teaching an organic-containing layer 54, an inorganic layer 56, a silicide 48 (it is a barrier metal inherent), forming a contact (see fig. 7,

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Abstract, col. 1, lines 55-65, col. 2, lines 25-65, col. 3, lines 1-10, 50-67, col. 4, lines 1-25, 45-55, col. 6, lines 20-67).

Claim Rejections - 35 USC § 103

- 14. The following is a quotation of 35 U.S.C. 103(a) which forms the basis for all obviousness rejections set forth in this Office action:
 - (a) A patent may not be obtained though the invention is not identically disclosed or described as set forth in section 102 of this title, if the differences between the subject matter sought to be patented and the prior art are such that the subject matter as a whole would have been obvious at the time the invention was made to a person having ordinary skill in the art to which said subject matter pertains. Patentability shall not be negatived by the manner in which the invention was made.
- 15. Claims 6-8 are rejected under 35 U.S.C. 103(a) as being unpatentable over Byrne (U.S. 5,136,364).

Byrne '364 discloses a substrate 10, a bonding pad 11, a two component passivation layer, a first dielectric layer (silicon dioxide), a second dielectric layer (silicon nitride) (it is known in the art than silicon nitride has a higher dielectric constant than silicon oxide), a third dielectric layer can be a polyimide layer, forming an opening to exposed the top surface of the bonding pad, depositing a barrier layer. It is teaching typically bumps are connected to the bonds pads. It also discloses a barrier layer comprising a nickel-vanadium layer; it has to be common to provide hermetic packaging.

16. Claims 1-5, 11-13, 15, 17-19 are rejected under 35 U.S.C. 103(a) as being unpatentable over Byrne (U.S. 5,136,364) in view of Byrne (U.S. 5,369,299) (previously applied).

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Byrne '364 does not specifically show the metal member being spaced apart from the bond pad by a gap as claimed. Nevertheless, this is conventional in the art as evidence by Byrne '299 (see above).

Byrne '299 cited "a more complete description of the protective seal is disclosed in U.S. Pat. No. 5,136,364 to Byrne which is incorporated herein by reference in its entirety", see col. 4, lines 64-66).

It would have been obvious to a person of ordinary skill in the art to include the metal member spaced from the bond pad by a gap as taught Byrne '299 because it would complete a semiconductor process which could provide a seal for a semiconductor device and it could exclude contaminants from the critical parts. In addition, Byrne '364 discloses as a practical manner, layers are applied over the entire IC wafer (see col. 2, lines 25-30).

17. Claims 9-10, 14, and 20 are rejected under 35 U.S.C. 103(a) as being unpatentable over Byrne '364 as applied to claims 1-8, 11-13, 15, and 17-19 above, and further in view of Mis et al (U.S. 5,767,010)

Mis et al. discloses a bump formed by electroplating techniques known to those having skill in the art, a barrier layer comprising a lower titanium layer (see figs. 5-6, 11-12, Abstract, col. 2, lines 15-55, col. 4, lines 5-20, col. 5, lines 15-20).

It would have be obvious to a person of ordinary skill in the art to modify Byrne's process by teaching the bump by electroplating and including a lower titanium layer as taught by Mis et al.

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because the titanium could prevent the under bump metallurgy layer from forming a residue on the underlying microelectronic device as taught Mis et al. (see Abstract).

18. Claim 16 is rejected under 35 U.S.C. 103(a) as being unpatentable over Byrne '364 as applied to claim 11 above, and further in view of Lou (U.S. 5,759,906).

Lou discloses as known in the art the used of a silicon oxide layer doped with fluorine as a dielectric layer used to reduce the capacitance between lines (see Abstract, col. 1, lines 55-67, col. 2, lines 5-15).

It would have be obvious to a person of ordinary skill in the art to modify Byrne's process by including a silicon oxide layer doped with fluorine as taught by Lou because it would reduce the capacitance between lines.

Conclusion

19. The prior art made of record and not relied upon is considered pertinent to applicant's disclosure. Mu et al. (U.S. 5,612,254) discloses a metal layer having a first member spaced apart from a second member by a gap, a dielectric layer 91 (silicon dioxide), another dielectric layer 92 (silicon nitride).

Harada (U.S. 5,260,600), Bryant et al. (U.S. 5,698,456), Sharma et al. (U.S. 4,927,505) and Michael (U.S. 5,563,102) disclose several steps related to Applicant's disclosure.

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20. Any inquiry concerning this communication or earlier communications from the examiner should be directed to Maria Guerrero whose telephone number is (703) 305-0162. The examiner can normally be reached on Monday-Friday from 8:00 Am to 4:30 Pm.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Carl Whitehead, can be reached on (703) 308-4940. The fax phone number for this Group is (703) 308-7722.

Any inquiry of a general nature or relating to the status of this application or proceeding should be directed to the Group receptionist whose telephone number is (703) 308-0956.

Carl Whitehead, Jr Supervisory Patent Examiner

Semiconductor Technology

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August 13, 1999